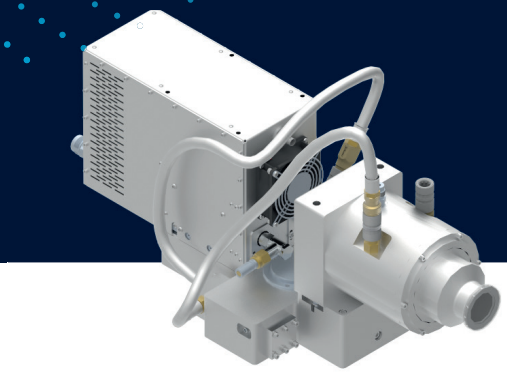
MUEGGE

REMOTE PLASMA SOURCE MA3000C-743BB

MICROWAVE PLASMA COMPONENTS
(2 KW / 3 KW / 2450 MHZ)

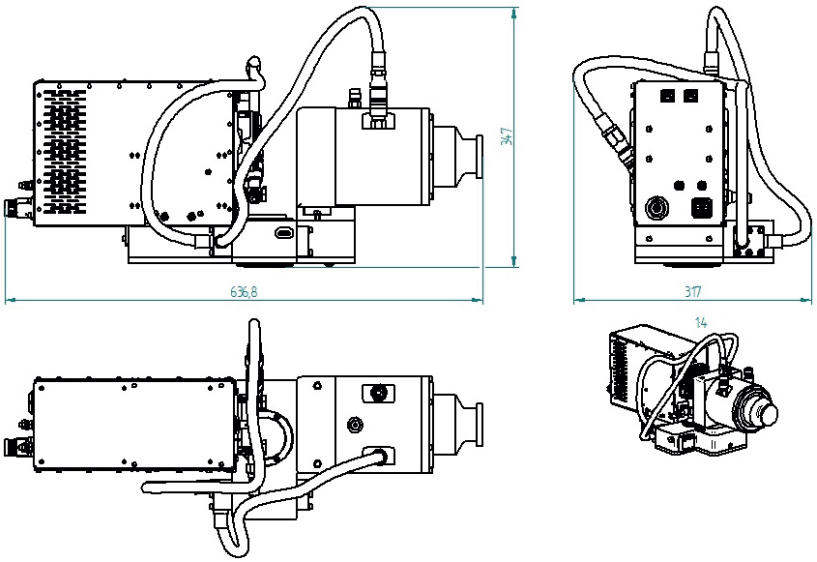


Features

- Compact Remote Plasma Source (RPS*) designed for the usage at vacuum chambers
- Superior design for photo resist stripping, chamber cleaning, isotropic etching and surface treatment
- Unparallelled cleaning results for process chambers with complex geometry
- Water cooled plasma zone
- Integrated magnetron head unit and launching unit with isolator
- Simple interfacing to any equipment (KF 40 or ISO-K63)

*(RPS: Plasma is only generated and burning in the RPS, only radicals are reaching the process chamber.)

Outline Dimensions (mm)



MUEGGE GmbH · Hochstr. 4–6 · 64385 Reichelsheim/Germany · Phone: (+49) 6164 9307-0 · info@muegge.de · www.muegge-group.com

MUEGGE

Specifications

Microwave-Power	3000 W cw max.
Frequency	2450 MHz ± 20 MHz
Magnetron	3000 W @ 2450 MHz
Applicator alignment	180 °
Prim. power circuit	-5100 DC / 0,84 A
Connection	Lemosa (ERA.3Y.415.CA)
Reactor outlet connector	KF 40
Primary control circuit	24 V / DC / 0,2 A
Connection	Various (RJ45)
Gas connection	Swagelok (SS-4-VCR-1-2RS)
Process gases	O_2, N_2, H_2, F_2, Ar, NH_3, CF_4 and other Fluorine based gases

Cooling water	≥ 4 (1,06) l/min (US.gal/min), ≤ 4 (58,02) bar (psi) @ 20 - 25 (68 - 77) °C (°F)
Connection magnetron unit	Stäubli (CBI 06.7151/IA/JV)
Connection plasma source	Stäubli (CBI 06.1151/IA)
Discharge tube	Ceramic
Dimensions	Compact design Width: 234 (9,21) mm (inch) Height: 365 (14,37) mm (inch) Depth: 670 (26,38) mm (inch)
Weight	Approximately: 29 (63,93) kg (lbs)
Conditions	5 °C (41 °F) – 45 °C (113 °F) non-condensing T max. = 45 °C (113 °F) < 3 h / day 80 % to 30 °C (86 °F), above linearly reduced to 50 % at 45 °C (113 °F)
Prim. heating circuit	230 / 208 V AC / 50 / 60 Hz / 0,38 A
Connection	Phoenix Contact (1605520)
Operating pressure	0.2 - 2 torr (maximum 5 torr)

Recommended system components

- Microwave power supply e.g. MX3000D-174KL